

RESPONSE UNDER 37 C.F.R. § 1.116
EXPEDITED PROCEDURE
GROUP 1792
PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q87267

Masahiko HATA

Appln. No.: 10/530,562

Group Art Unit: 1792

Confirmation No.: 8996

Examiner: Felisa Carla HITESHEW

Filed: April 7, 2005

For: METHOD FOR PRODUCING THIN FILM CRYSTAL WAFER, SEMICONDUCTOR
DEVICE USING THE SAME AND METHOD FOR PRODUCING THE
SEMICONDUCTOR DEVICE

RESPONSE UNDER 37 C.F.R. § 1.116

MAIL STOP AF

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated July 22, 2009, please consider the remarks as
submitted herewith on the accompanying pages.

TABLE OF CONTENTS

REMARKS.....	2
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